



PATENT  
81877.0007

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the application of:  
Norikazu MIZUNO et al.

Serial No: 09/670,917

Confirmation No.: 1895

Filed: September 29, 2000

For: Semiconductor Device  
Manufacturing Method and  
Apparatus For Removing Silicon  
Nitride Formed in A Reaction  
Container (As Amended)

Art Unit: 2822

Examiner: Guerrero, Maria F.

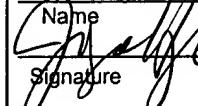
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Name

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Signature

Date

**PETITION FOR EXTENSION OF TIME**

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the Commissioner for a three-month extension of time extending to September 27, 2004, the period for response to the Office Action dated March 25, 2004. Please charge the fee of \$950 for this extension to Deposit Account No. 50-1314. The responsive paper(s) are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

By:

  
Troy M. Schmelzer  
Registration No. 36,667  
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Date: September 24, 2004

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